

**AMENDMENTS TO THE CLAIMS**

*This listing will replace all prior versions, and listings, of claims in the application:*

1. (Currently amended) A method for measuring a measurement object having at least one reference structure for defining an object-fixed object coordinate system, with the aid of a measuring system comprising at least one sensor system for recording a contour of the measurement object in a measurement coordinate system, the method comprising the following steps:

positioning the measurement object in a measurement position in the coverage range of the sensor system;

establishing the position of the object coordinate system by means of the reference structure;

linking the object coordinate system with the measurement coordinate system;

rotating the sensor system about a ~~rotation axis relative to~~ the measurement object for determining contour data; and

processing the contour data, whilst taking account of the position of the object coordinate system in an evaluation unit.

2. (Currently amended) The [[M]] method according to claim 1, wherein during the measurement, the measurement object is so fixed by a centering device that accessibility to the reference structure is not impeded.

3. (Currently amended) The [[M]] method according to claim 2, wherein the measurement object is fixed in the measurement position in such a way that the reference structure is accessible for establishing the measurement object position, the measurement object being ~~substantially~~ rotation-like with respect to a measurement object axis, wherein the reference structure is positioned within the outer contour of the measurement object ~~in the vicinity of~~ at or near the measurement object axis and a centering device for centering the measurement object acts

on the outer contour of the measurement object.

4. (Currently amended) The ~~[[M]]~~method according to claim 2, wherein a reference device for establishing the position of the object coordinate system scans the ~~substantially~~ freely accessible reference structure.

5. (Currently amended) The ~~[[M]]~~method according to claim 4, wherein the reference device scans in noncontacting manner the ~~substantially~~ freely accessible reference structure.

6. (Currently amended) The ~~[[M]]~~method according to claim 1, wherein a reference device performs a mechanical orientation of the measurement object by means of the reference system for establishing the position of the object coordinate system.

7. (Currently amended) The ~~[[M]]~~method according to claim 1, wherein a shape and/or position variation of at least one measurement object surface portion provided for engagement on an object surface, oriented ~~substantially~~ orthogonally to a rotation axis of the sensor system and formed on the measurement object is determined by means of the sensor system and/or reference device.

8. (Currently amended) The ~~[[M]]~~method according to claim 1, wherein a marking is made on the measurement object defining a characteristic measurement point by a marking device connected to the sensor system.

9. (Currently amended) The ~~[[M]]~~method according to claim 1, wherein the measurement object is conveyed ~~substantially~~ linearly between an insertion opening and a discharge opening of the measurement system.

10. (Currently amended) The ~~[[M]]~~method according to claim 1, wherein measurement data of the sensor system are linked with measurement data of the reference device for determining

wall thicknesses.

11. (Currently amended) A [[D]] device for measuring a measurement object having at least one reference structure for defining an object-fixed object coordinate system having a measuring system with at least one sensor system for recording a contour of the measurement object in a measurement coordinate system and a reference device for establishing the position of the object coordinate system with the aid of the reference structure, the sensor system being mounted in rotary manner relative to the measurement object in such a way that the sensor system is rotatable around the measurement object.

12. (Currently amended) The [[D]] device according to claim 11, wherein there is a centering device for a positioning and/or fixing of the measurement object in the measurement position before and/or during measurement.

13. (Currently amended) The [[D]] device according to claim 11, wherein the reference device is set up for a noncontacting reference structure scanning.

14. (Currently amended) The [[D]] device according to claim 11, wherein the reference device is constructed for mechanically centering the measurement object with the aid of the reference structure.

15. (Currently amended) The [[D]] device according to claim 11, wherein the sensor system and/or reference device is provided for determining the flatness and/or orientation of a measurement object surface portion provided on the measurement object, oriented substantially orthogonally to a rotation axis of the sensor system and constructed for engagement on an object surface.

16. (Currently amended) The [[D]] device according to claim 11, wherein a marking device for making a marking on the measurement object is provided on the sensor system and/or

reference device.

17. (Currently amended) The ~~[[D]]~~ device according to claim 11, wherein the reference device is arranged in rotary manner substantially coaxially to a rotation axis of the sensor system.

18. (Currently amended) The ~~[[D]]~~ device according to claim 11, wherein integration takes place into a conveying device, particularly a linear conveying system.

19. (Currently amended) The ~~[[D]]~~ device according to claim 11, wherein there are size determination means for a basic positioning of the sensor system and/or reference device.

20. (Currently amended) The ~~[[M]]~~ method according to claim 6, wherein the reference structure is measured.

21. (Currently amended) The ~~[[M]]~~ method according to claim 9, wherein the measurement object is conveyed ~~substantially~~ perpendicular to the sensor system rotation axis.

22. (New) The method according to claim 1, wherein the sensor system is rotated about a rotation axis enclosed by a circumference of the measuring object.

23. (New) The method according to claim 1, wherein the measurement comprises a complete rotation of the sensor system about a rotation axis.

24. (New) The method according to claim 1, wherein the measuring object rests during the measurement.

25. (New) The method according to claim 1, wherein the measurement object is a vehicle wheel.

26. (New) The device according to claim 11, wherein the sensor system is rotatable about a rotation axis enclosed by a circumference of the measuring object.

27. (New) The device according to claim 11, wherein the measurement comprises a complete rotation of the sensor system about a rotation axis.

28. (New) The device according to claim 11, wherein the measuring object rests during the measurement.

29. (New) The device according to claim 11, wherein the measurement object is a vehicle wheel.